



# The adsorption and reactions of $\text{SiCl}_x$ ( $x = 0-4$ ) on hydroxylated $\text{TiO}_2$ anatase (101) surface: A computational study on the functionalization of titania with $\text{Cl}_2\text{Si}(\text{O})\text{O}$ adsorbate

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## ABSTRACT

The adsorption and reactions of the  $\text{SiCl}_x$  ( $x = 0-4$ ) on the hydroxylated  $\text{TiO}_2$  anatase (101) surface have been investigated by using periodic density functional theory calculations in conjunction with the projected augmented wave (PAW) approach. The adsorption and reactions tend to occur more readily on the 'O<sub>w</sub>' site derived from water than the 'O<sub>s</sub>' site from  $\text{TiO}_2$  as revealed by the potential energy profiles and adsorption energies. The stepwise reactions of  $\text{SiCl}_x$  can be achieved by dehydrochlorination taking place by three paths: O<sub>w</sub>-path, cross-path, and O<sub>s</sub>-path. The O<sub>w</sub>-path is the lowest energy path, in which  $\text{Cl}_2\text{Si}-\text{O}_w(\mathbf{a})$  and  $\text{Cl}_2\text{Si}-(\text{O}_w)\text{O}_w(\mathbf{a})$  are the main products formed by spontaneous reactions. The ready formation and the high stability of  $\text{Cl}_2\text{Si}-(\text{O}_w)\text{O}_w(\mathbf{a})$  suggest that it can be employed as a molecular linker for Si and other semiconductor quantum dot growth on titania through its high reactivity towards  $\text{SiH}_x$  radicals and metal alkyls, respectively.

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## 1. Introduction

Titanium dioxide ( $\text{TiO}_2$ ) has been shown to be a very versatile material as demonstrated in numerous theoretical and experimental studies because of its promising applications to fabrication of photocatalysts and photoelectrochemical devices [1,2]. The photo-physics of  $\text{TiO}_2$  sensitized by a variety of dyes [3–5], polymers [6,7], and semiconductors [8–10] have been widely studied in particular for solar energy conversions. One of the well-known semiconductor quantum dots for solar cell applications is silicon, which has been studied extensively [11–20]. In 2004, the growth of Si on  $\text{TiO}_2$  rutile (110) surface was reported by Abad et al. [21].

To improve the heterogeneous interface and achieve higher photovoltaic efficiencies, inorganic linkers have been employed for semiconductor quantum dots growth on  $\text{TiO}_2$  [22–27]. Inorganic linkers for pure  $\text{TiO}_2$  anatase (101) and rutile (110) surfaces,  $\text{SiH}_x$ , have been studied theoretically by Huang et al. [28]. However, the  $\text{TiO}_2$  surface is known to be readily covered with hydroxyl groups in the water-rich environment [29–33].  $\text{SiH}_x$ , particularly  $\text{SiH}_4$ , was found to interact weakly with the hydroxylated  $\text{TiO}_2$  surface and thus may not be a good linker between silicon and hydroxylated  $\text{TiO}_2$  surface. Based on the known propensity of  $\text{SiCl}_4$  reactions with HO-containing molecules and their common use as

Si sources in the silica-coating process [34,35],  $\text{SiCl}_x$  ( $x = 1-4$ ) is expected to be a potential linker for the hydroxylated  $\text{TiO}_2$  surface.

In this work, we study the adsorption of  $\text{SiCl}_x$  with the hydroxylated  $\text{TiO}_2$  anatase (101) surface as well as their decomposition reactions by dehydrochlorination employing the density functional theory (DFT). The potential energy profiles of the reactions are calculated by nudged elastic band (NEB) method. The results of this study should be useful for understanding the mechanism for  $\text{SiCl}_x$  adsorption and decomposition on the  $\text{TiO}_2$  surface for fabrication of optoelectronic devices and solar cells.

## 2. Computational methods and models

All calculations were performed by the spin-polarized DFT with the projected augmented wave method (PAW) [36] as implemented in the Vienna ab initio simulation package (VASP) [37,38]. The ionic cores were described by the generalized gradient approximation (GGA) with the PW91 [39] formulation which had been shown to work well for gas-surface reactions [22,27,40,41]. The electronic orbitals were represented by the plane-wave expansion including all the plane waves with their kinetic energies smaller than the chosen cut-off energy,  $\hbar^2/2m < E_{\text{cut}}$  (500 eV), which ensures the convergence. The nudged elastic band (NEB) method [42] was applied to locate the transition states (TSs), up to eight images for each calculated TS. All the transition structures were verified by the frequency calculations.

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The TiO<sub>2</sub> NP film is a polycrystalline material with different phases dependent on annealing temperature [43–45], particle size [46–48], and shape [49]. The three different phases of TiO<sub>2</sub> are rutile, anatase, and brookite. For solar cell applications, Park et al. showed that electron transport is slower in rutile films by intensity-modulated photocurrent and scanning electron microscopy [50]. Anatase is the preferred phase of TiO<sub>2</sub> for catalysis, photocatalysis, and solar cell applications [1,2,51,52], and (101) is the most stable surface of the anatase surface [53]. Hence, we attempt to characterize SiCl<sub>x</sub> reactions on the TiO<sub>2</sub> anatase (101) surface in this study.

The bulk TiO<sub>2</sub> was optimized first with (4 × 4 × 4) Monkhorst-Pack k-points. Based on the optimized bulk TiO<sub>2</sub> geometry, the surface super cell consisting of 24 [TiO<sub>2</sub>] units (three Ti layers, see Supporting Information) was modeled as periodically repeated slabs, separated by a vacuum space greater than 13 Å, which guarantees no interactions between the slabs. The lowest layers of each slab were fixed to preserve the calculated bulk parameters, while the remaining layers were fully relaxed to simulate the surface behavior during the calculations. The (4 × 6 × 1) Monkhorst-Pack k-points were used for the TiO<sub>2</sub> surface calculation. Gas-phase molecules were simulated in a 20 Å cubic box, which is large enough to ignore interactions between each periodic gas molecules.

### 3. Results and discussion

To verify the reliability of the computational results, we first compared the calculated bulk lattice constants with experimental values. The predicted lattice constants of TiO<sub>2</sub> anatase are  $a = 3.824$  Å and  $c = 9.678$  Å, which are in good agreement with the experimental values, [54,55]  $a = 3.872$ – $3.875$  Å and  $c = 9.502$ – $9.514$  Å. The predicted fractional coordinate is  $u = 0.208$ , which also agrees well with the experimental value,  $u = 0.208$  [56]. In addition, the predicted adsorption energy of H<sub>2</sub>O on TiO<sub>2</sub> anatase (101) surface is also in good agreement with experimental results, which will be discussed below. The good prediction of bulk geometry and adsorption energy of H<sub>2</sub>O on TiO<sub>2</sub> anatase (101) surface supports the validity of the surface model. The geometries of gas phase molecules, SiCl<sub>x</sub>(g) ( $x = 1$ – $4$ ), are also examined, and the comparison of the experimental and calculated results is made in Table S1 of Supporting Information. Our predicted results are in

very good agreement with the experimental and other calculated data.

#### 3.1. Hydroxylated TiO<sub>2</sub> anatase (101) surface

The generally accepted scheme for the formation of hydroxylated TiO<sub>2</sub> surface(29–33) is shown in Fig. 1a. There are four different adsorption sites on the clean TiO<sub>2</sub> surfaces: Ti<sub>5c</sub> (fivefold coordinated titanium), Ti<sub>6c</sub> (sixfold coordinated titanium), O<sub>2c</sub> (twofold coordinated oxygen or bridged oxygen), and O<sub>3c</sub> (threefold coordinated oxygen). The two unsaturated sites, Ti<sub>5c</sub> and O<sub>2c</sub>, are more reactive [57,58]. In the hydroxylation reaction, H<sub>2</sub>O molecule firstly adsorbs at the Ti<sub>5c</sub> site, forming H<sub>2</sub>O–Ti<sub>5c</sub>(a), and then dissociates to HO and H as described below. The H atom binds to the bridge oxygen (O<sub>2c</sub>) and co-adsorbs with the HO radical at the Ti<sub>5c</sub> site forming HO–Ti<sub>5c</sub>,H–O<sub>2c</sub>(a). All the calculated energies at 1 ML are also shown in Fig. 1a. The adsorption energy of H<sub>2</sub>O–Ti<sub>5c</sub>(a) at 1 ML is 17.3 kcal/mol, which is in good agreement with calculated (15.9–16.6 kcal/mol) [57,59,60] and experimental (16.6–17.1 kcal/mol)[61] results. The transition state lies 5.0 kcal/mol below the reactants, TiO<sub>2</sub>(s) + H<sub>2</sub>O(g); the overall reaction is exothermicity of 10.3 kcal/mol. Hence, the formation of the hydroxylated TiO<sub>2</sub> is a spontaneous reaction, as observed experimentally [29,32,62].

There are two types of hydroxyl groups on the TiO<sub>2</sub> surface. One derived from the H<sub>2</sub>O molecule, and the other one is formed by H reaction with the O<sub>2c</sub> of the TiO<sub>2c</sub> surface. To distinguish the two types of oxygen sources, we name the O atoms from H<sub>2</sub>O and TiO<sub>2</sub> as ‘O<sub>w</sub>’ and ‘O<sub>s</sub>’, respectively. The calculated geometry of the fully hydroxylated TiO<sub>2</sub> anatase (101) surface is shown in Fig. 1b. The bond length and bond angles of H–O<sub>w</sub> and H–O<sub>w</sub>–Ti<sub>5c</sub> are 0.971 Å and 122.7°, respectively, while those for H–O<sub>s</sub> and H–O<sub>s</sub>–Ti<sub>5c</sub> are 0.972 Å and 121.3°. A Bader atomic charge analysis [63] shows the two types of hydroxyl groups have similar charge distribution. The charges of two H atoms are 1.00 e, and those of ‘O<sub>w</sub>’ and ‘O<sub>s</sub>’ are 1.67 e and 1.60 e.

However, the reactivities of these two types of hydroxyl groups are different due to the surface morphology. The ‘O<sub>w</sub>’ and ‘O<sub>s</sub>’ atoms lie above the first Ti layer by 1.822 and 0.627 Å respectively. In other words, ‘O<sub>w</sub>’ protrudes out of the surface more evidently than ‘O<sub>s</sub>’ does. Thus gas molecule can more easily adsorb on the ‘O<sub>w</sub>’ site than on the ‘O<sub>s</sub>’ site as will be reflected by the differences

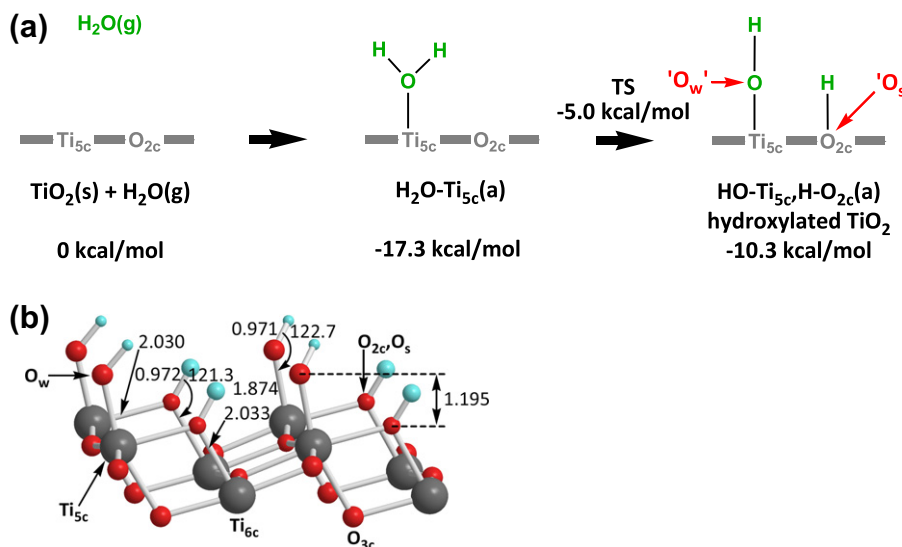
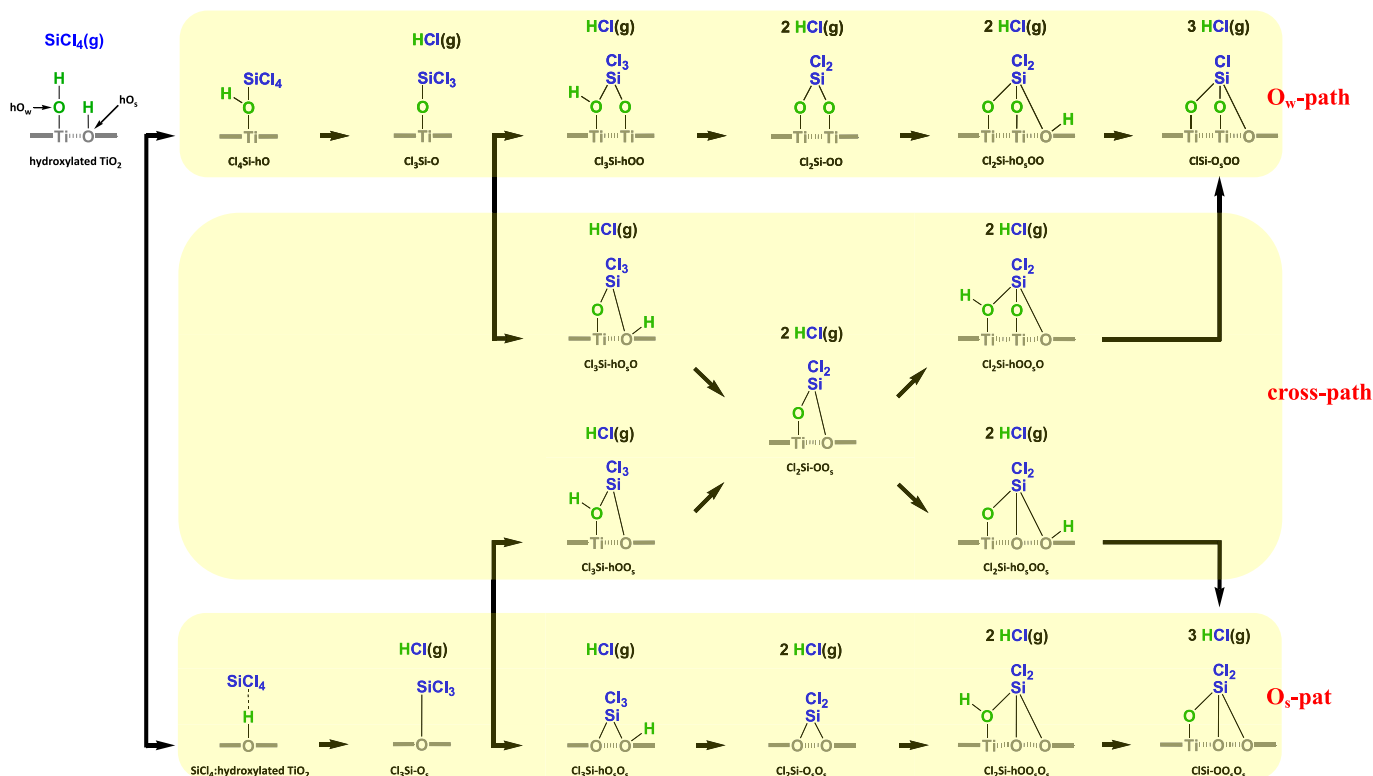


Fig. 1. (a) Scheme of the formation of hydroxylated TiO<sub>2</sub> surface. All the energies are referred to the energy of TiO<sub>2</sub>(s) + H<sub>2</sub>O(g). (b) The configuration of fully hydroxylated TiO<sub>2</sub> anatase (101) surface. TiO<sub>2</sub> model is only shown with one Ti layer. The bond length and angle are in Å and degree, respectively.



**Fig. 2.** Scheme of  $\text{SiCl}_x$  decomposition on the hydroxylated  $\text{TiO}_2$  anatase (101) surface. (For the surface sketch, only the adsorbed sites are shown. The reactions are all in mass balance.)

in adsorption energies and potential energy profiles discussed below.

### 3.2. Adsorption and reactions of $\text{SiCl}_x$ ( $x = 0-4$ ) on the $\text{TiO}_2$ anatase (110) surface

To generalize the nomenclature,  $\text{Cl}_x\text{Si}-(\text{h})\text{P}_1\dots\text{P}_y(\mathbf{a})$  ( $\text{P}_1\dots\text{P}_y = \text{O}_w$  or  $\text{O}_s$ ) is named for  $\text{SiCl}_x$  adsorbates formed by the Si head bonding with  $\text{P}_1, \text{P}_2, \dots, \text{P}_y$  sites, which can be one to three sites ( $y = 1-3$ ). The prefixed 'h' denotes an H atom adsorbed concurrently on the  $\text{P}_1$  site. For example,  $\text{Cl}_x\text{Si}-\text{hO}_s\text{O}_w(\mathbf{a})$  represents  $\text{SiCl}_x$  doubly bonded with  $\text{O}_s$  and  $\text{O}_w$  atoms with a hydrogen atom simultaneously bonding with the  $\text{O}_s$  atom.

#### 3.2.1. Dehydrochlorination reactions

Atomic layer growth of metal oxide can occur on a hydroxylated surface with  $\text{MCl}_4$  ( $\text{M} = \text{Si}$  [64] or  $\text{Ti}$  [65]) by dehydrochlorination. A general reaction can be illustrated by  $\text{HO}(\text{a}) + \text{MCl}_4(\text{g}) \rightarrow \text{Cl}_3\text{MO}(\text{a}) + \text{HCl}(\text{g})$ . HCl can be formed from the reaction of one of the Cl atoms of  $\text{MCl}_4$  with one of the H atoms on the hydroxylated surface. Hence,  $\text{SiCl}_x$  decomposition on the hydroxylated  $\text{TiO}_2$  surface can be achieved by a similar dehydrochlorination reaction.

The possible mechanisms of  $\text{SiCl}_x$  decomposition reactions are shown in Fig. 2. Three reaction pathways are considered. The reaction following the ' $\text{O}_w$ ' bonding site first (the order is  $\text{O}_w-\text{O}_w-\text{O}_s$ ) is named  $\text{O}_w$ -path, and the one following the ' $\text{O}_s$ ' bonding site first (the order is  $\text{O}_s-\text{O}_s-\text{O}_w$ ) is named  $\text{O}_s$ -path. The remaining reaction is named cross-path, which may have the order of  $\text{O}_w-\text{O}_s-\text{O}_w$  or  $\text{O}_s-\text{O}_w-\text{O}_s$ .

#### 3.2.2. The lowest energy path

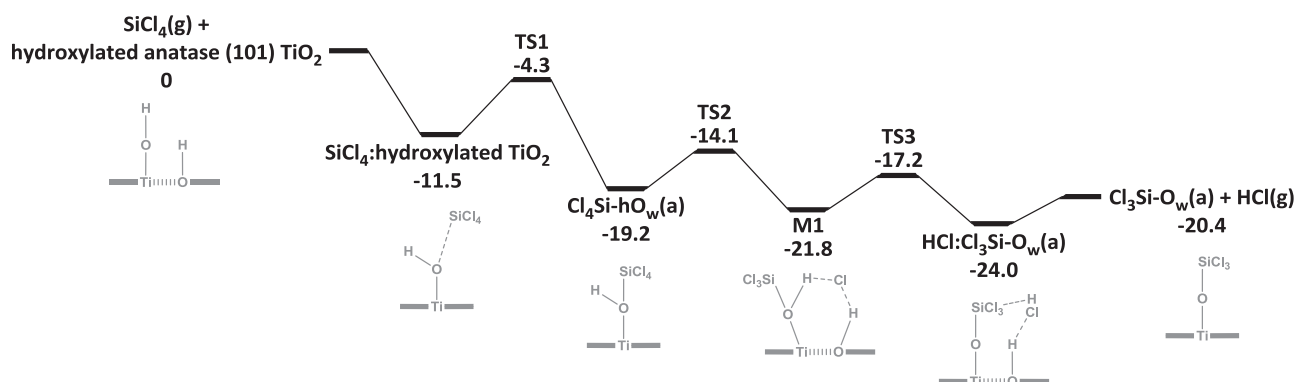
In our calculations, we find that the  $\text{O}_w$ -path is the lowest energy path, and the  $\text{O}_s$ -path is the highest energy path. The complete potential energy profiles are shown in Supporting Information of

Fig. S2. As shown in the figure, the highest energy barriers of the  $\text{O}_w$ -path, cross-path and  $\text{O}_s$ -path are 9.7, 15.9, and 37.6 kcal/mol, respectively. As mentioned above, the gas molecule can attach to the protruding ' $\text{O}_w$ ' site more readily than to the ' $\text{O}_s$ ' site. In the following, we only discuss the  $\text{O}_w$ -path mechanism.

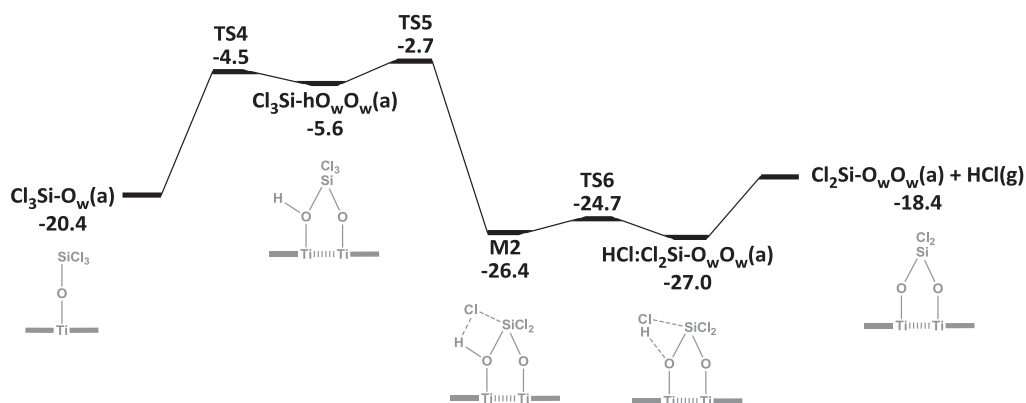
Fig. 3 shows the potential energy profile describing the  $\text{O}_w$ -path mechanism. The simplified geometries depicted in Fig. 3 are shown in Fig. 4. As illustrated in Fig. 3a,  $\text{SiCl}_4$  physically associates with one of the  $\text{O}_w$  atoms on the fully hydroxylated  $\text{TiO}_2$  anatase surface firstly with an association energy of 11.5 kcal/mol and the  $\text{Si}\dots\text{O}_w$  distance of 3.926 Å. Overcoming a small energy barrier of 7.2 kcal/mol (**TS1**, Fig. 4b), the  $\text{SiCl}_4$  molecule can chemically bond with the surface with an  $\text{Si}-\text{O}_w$  bond of 1.753 Å, forming  $\text{Cl}_4\text{Si}-\text{hO}_w(\mathbf{a})$  (Fig. 4c) with an exothermicity of 7.7 kcal/mol. The surrounding H atoms can undergo hydrogen-bonding with the Cl atoms in  $\text{Cl}_4\text{Si}-\text{hO}_w(\mathbf{a})$ . Dehydrochlorination occurs when one of the Cl atoms is attracted by one of the nearest H atoms on the hydroxylated surface; the barrier for the process at **TS2** is 14.1 kcal/mol below the reactants (Fig. 4d), giving an  $\text{H}\dots\text{Cl}$  bonding complex **M1** (Fig. 4e) with an overall exothermicity of 21.8 kcal/mol. The distances of  $\text{Cl}\dots\text{Si}$  and  $\text{Cl}\dots\text{H}$  of **M1** are 3.671 and 1.874 Å, respectively. Crossing the small **TS3** (Fig. 4f) barrier of 4.6 kcal/mol, one HCl molecule is produced to form a hydrogen bonding complex **HCl:Cl<sub>3</sub>Si-O<sub>w</sub>(a)** (Fig. 4g) with an overall exothermicity of 24.0 kcal/mol. The physically adsorbed HCl(g) can be released endothermically with 3.6 kcal/mol, producing  $\text{Cl}_3\text{Si}-\text{O}_w(\mathbf{a})$  (Fig. 4h) on the surface which has a binding energy as high as 133 kcal/mol (see Table 1).

Starting from  $\text{Cl}_3\text{Si}-\text{O}_w(\mathbf{a})$ , the Si atom can doubly bond with another oxygen atom of ' $\text{O}_w(\text{H})$ ' to form  $\text{Cl}_3\text{Si}-\text{hO}_w\text{O}_w(\mathbf{a})$  (Fig. 4j) by overcoming the **TS4** barrier of 14.8 kcal/mol; the complex lies 4.5 kcal/mol below the initial reactants. The bond lengths of  $\text{Si}-\text{O}_w$  and  $\text{Si}-\text{O}_w(\text{H})$  are 1.643 and 1.896 Å, respectively. The longer bond length of  $\text{Si}-\text{O}_w(\text{H})$  resulted from the additional bonding with the hydrogen atom. The over-bonding of the Si atom in

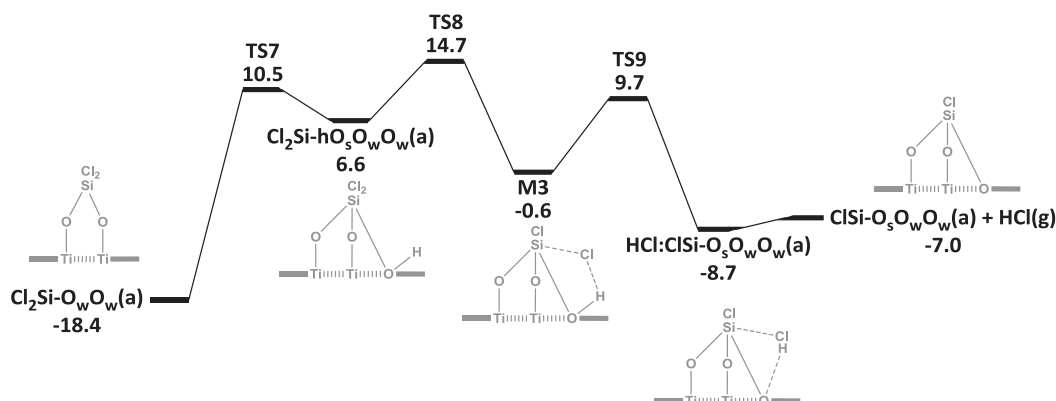
## (a) First Dehydrochlorination



## (b) Second Dehydrochlorination



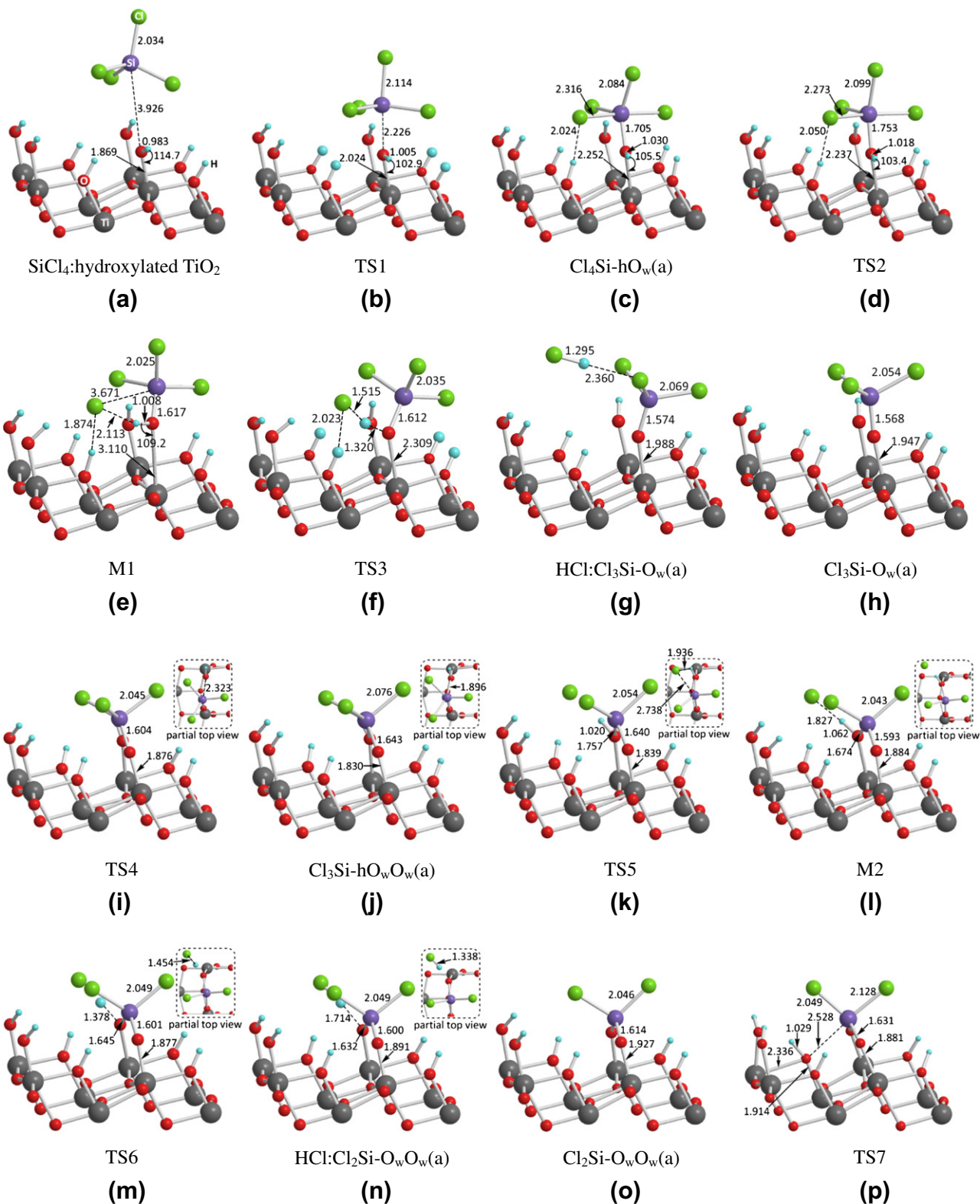
## (c) Third Dehydrochlorination



**Fig. 3.** Schematic potential energy profiles for the most possible reaction path of  $\text{SiCl}_x$  decomposition on the hydroxylated  $\text{TiO}_2$  anatase (101) surface. (For the surface sketch, only the adsorbed sites are shown. In figure (b) and (c), one and two  $\text{HCl}(\text{g})$  are omitted for brevity; they are included in energy calculations and are mass-balanced.)

$\text{Cl}_3\text{Si-hO}_w\text{O}_w(\text{a})$  enhances the hydrogen bonding between one of Cl atoms with the H attached to the  $\text{O}_w$  atom bonding with Si by overcoming a small energy barrier of 2.9 kcal/mol (**TS5**, Fig. 4k) forming the intermediate **M2** (Fig. 4i) in which the  $\text{Cl}\cdots\text{H}$  distance is 1.827 Å. The second dehydrochlorination can be achieved readily by overcoming a small barrier **TS6** (Fig. 4m) of 1.7 kcal/mol, giving **HCl:Cl<sub>2</sub>Si-O<sub>w</sub>O<sub>w</sub>(a)** (Fig. 4n) with a small exothermicity of 0.6 kcal/mol. The desorption of the physically adsorbed  $\text{HCl}(\text{a})$  requires 8.6 kcal/mol to give the highly stable, doubly bonded **Cl<sub>2</sub>Si-O<sub>w</sub>O<sub>w</sub>(a)** (Fig. 4o) on the surface. Similar to the reaction of  $\text{Cl}_3\text{Si-O}_w(\text{a}) \rightarrow \text{Cl}_3\text{Si-hO}_w\text{O}_w(\text{a})$ , the Si atom of **Cl<sub>2</sub>Si-O<sub>w</sub>O<sub>w</sub>(a)** can triply

bond with one more closest oxygen site, ' $\text{O}_5$ ', forming **Cl<sub>2</sub>Si-hO<sub>5</sub>-O<sub>w</sub>O<sub>w</sub>(a)** (Fig. 4q) by overcoming a high energy barrier of 28.9 kcal/mol (**TS7**, Fig. 4p) with an endothermicity of 25.0 kcal/mol. The high energy barrier and the endothermicity for the formation of the triply bonded adsorbate make the doubly bonded **Cl<sub>2</sub>Si-O<sub>w</sub>O<sub>w</sub>(a)** adsorbate the major terminal product. Due to the surface morphology, it is also impossible to attach to another ' $\text{O}_w$ ' site for **Cl<sub>2</sub>Si-O<sub>w</sub>O<sub>w</sub>(a)** along the  $\text{O}_w$ -path. One of Cl atoms in **Cl<sub>2</sub>Si-hO<sub>5</sub>-O<sub>w</sub>O<sub>w</sub>(a)** can in principle undergo further dehydrochlorination through hydrogen bonding to form the third intermediate **M3** (Fig. 4s) with an exothermicity of 7.2 kcal/mol by overcoming the



**Fig. 4.** Optimized geometries of adsorbed  $\text{SiCl}_x$  on the hydroxylated  $\text{TiO}_2$  anatase (101) surface.  $\text{TiO}_2$  model is only shown with one Ti layer. The bond length and angle are in Å and degree, respectively.

energy barrier of 8.1 kcal/mol (**TS8**, Fig. 4r). The distance of the Cl...H hydrogen bonding in **M3** (Fig. 4s) is 2.085 Å. The third dehydrochlorination can occur by overcoming **TS9** (Fig. 4t) with a barrier of 10.3 kcal/mol and an exothermicity of 8.1 kcal/mol to form **HCl:ClSi-O<sub>w</sub>O<sub>w</sub>(a)** (Fig. 4u). The HCl(g) can be released from **HCl:ClSi-O<sub>w</sub>O<sub>w</sub>(a)** with only a small endothermicity of

0.3 kcal/mol. In **ClSi-O<sub>w</sub>O<sub>w</sub>(a)**, all the H atoms are too far from the Cl atom to generate the fourth dehydrochlorination (Fig. 4v), it is left on the surface with an overall exothermicity of 7.0 kcal/mol from the reactants,  $\text{SiCl}_4(\text{g}) + \text{hydroxylated anatase (101) TiO}_2$ .

In the  $\text{O}_w$ -path described above, **Cl<sub>3</sub>Si-O<sub>w</sub>(a)** and **Cl<sub>2</sub>Si-O<sub>w</sub>O<sub>w</sub>(a)** can be formed without thermal activation as all the transition

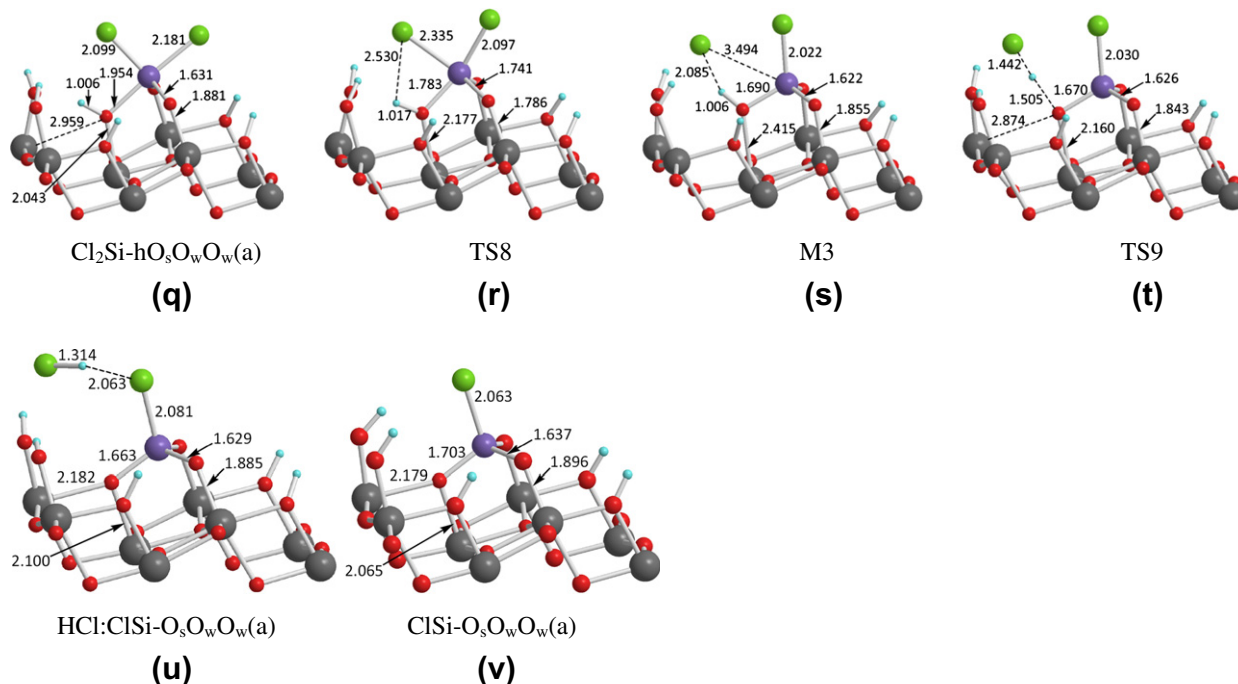


Fig. 4 (continued)

**Table 1**  
Calculated adsorption energies of  $\text{SiCl}_x$  on the hydroxylated  $\text{TiO}_2$  surface (kcal/mol).

Adsorbate	Site	Figure	$E_{ads}$	Adsorbate	Site	Figure	$E_{ads}$
$\text{SiCl}_4$	$\text{hO}_s$	4a, S3a	11.5, 8.9	$\text{SiCl}_3$	$\text{O}_s$	S3q	112.5
	$\text{hO}_w$	4c	19.2		$\text{O}_w$	4h	133.2
$\text{SiCl}_3$	$\text{hO}_s\text{O}_s$	S3h	78.6	$\text{SiCl}_2$	$\text{O}_s\text{O}_s$	S3k	148.0
	$\text{hO}_s\text{O}_w$	S3ae	104.3		$\text{O}_s\text{O}_w$	S3ai	192.1
	$\text{hO}_w\text{O}_s$	S3s	105.7	$\text{O}_w\text{O}_w$	4o	211.2	
	$\text{hO}_w\text{O}_w$	4j	118.3	$\text{SiCl}$	$\text{O}_s\text{O}_w\text{O}_w$	4v	313.0
$\text{SiCl}_2$	$\text{hO}_s\text{O}_w\text{O}_w$	4q	185.1		$\text{O}_w\text{O}_s\text{O}_s$	S3ac	300.7
	$\text{hO}_w\text{O}_s\text{O}_w$	S3ak	191.8				
	$\text{hO}_w\text{O}_s\text{O}_s$	S3m	186.3				
	$\text{hO}_s\text{O}_w\text{O}_s$	S3y	173.9				

states (**TS1–TS6**) are lower than the initial reactants. As a result, the most likely product in the energetically downhill reactions,  **$\text{Cl}_2\text{Si-O}_w\text{O}_w(\mathbf{a})$** , can be formed with an exothermicity of 27.0 kcal/mol relative to the reactants. The high barrier at **TS8** (33 kcal/mol) for its decomposition by dehydrogenation to  **$\text{ClSi-O}_s\text{O}_w\text{O}_w(\mathbf{a})$**  should make  **$\text{Cl}_2\text{Si-O}_w\text{O}_w(\mathbf{a})$**  the most abundant species produced in the reaction of  $\text{SiCl}_4$  with the hydroxylated  $\text{TiO}_2$  (101) anatase surface.

### 3.2.3. Adsorption energies

The adsorption energies of the species  $\text{SiCl}_x$  on the hydroxylated  $\text{TiO}_2$  surface are listed in Table 1. The adsorption energies were calculated by the following equation:

$$E_{ads} = -(E_{total} - E_{surf} - E_{gas})$$

where  $E_{total}$ ,  $E_{gas}$ , and  $E_{surf}$  are the electronic energies of the adsorbed species on the surface, a gas-phase molecule, and the surface, respectively. The  $E_{surf}$  for  **$\text{Cl}_3\text{Si-hO}_w\text{O}_w(\mathbf{a})$** , for example, is the energy of a fully hydroxylated  $\text{TiO}_2$  surface with one hydrogen vacancy for molecular adsorption.

As shown in Table 1, for the saturated  **$\text{Cl}_{x-1}\text{Si-P}_1 \dots \text{P}_{4-x}(\mathbf{a})$** , the average adsorption energies are 128, 170, and 307 kcal/mol for singly, doubly, and triply bonded configurations, respectively. The

adsorption energies increase with the number of bondings. The same trend was noted for the over-bonded  **$\text{Cl}_x\text{Si-hP}_1 \dots \text{P}_{4-x}(\mathbf{a})$**  with an Cl atom attached to the  $\text{P}_1$  (oxygen) site, 13, 102, 184 kcal/mol, respectively. For the same number of binding sites, the adsorption energies of the over-bonded configurations are much lower than those of bond saturated configurations. As mentioned above, the gas phase molecules tend to adsorb on an 'O<sub>w</sub>', which is supported by the adsorption energies shown in Table 1. In the case of  $\text{SiH}_x$  radical adsorptions ( $x = 1-3$ ) [28], the adsorption energies of  **$\text{H}_3\text{Si-O}_w(\mathbf{a})$**  (133.2 kcal/mol),  **$\text{H}_2\text{Si-O}_w\text{O}_w(\mathbf{a})$**  (211.2 kcal/mol),  **$\text{HSi-O}_s\text{O}_w\text{O}_w(\mathbf{a})$**  (313.0 kcal/mol) are all larger than those of  **$\text{H}_3\text{Si-O}_s(\mathbf{a})$**  (97.6 and 112.5 kcal/mol),  **$\text{H}_2\text{Si-O}_s\text{O}_s(\mathbf{a})$**  (148.0 kcal/mol),  **$\text{HSi-O}_w\text{O}_s\text{O}_s(\mathbf{a})$**  (300.7 kcal/mol). A similar trend was observed in the over-bonded cases. Finally, these high adsorption energies also confirm the stability of  $\text{SiCl}_x$  adsorption on the hydroxylated surface.

## 4. Conclusions

The  $\text{SiCl}_x$  adsorption and reaction on the hydroxylated anatase (101)  $\text{TiO}_2$  surface have been studied by periodic DFT calculations. The results firstly show that the hydroxylated anatase (101)  $\text{TiO}_2$  surface can be formed spontaneously by the reaction  $\text{H}_2\text{O}(\text{g}) +$

anatase (101) TiO<sub>2</sub> surface. There are two kinds of oxygen adsorption sites, 'O<sub>w</sub>' and 'O<sub>s</sub>', on the fully hydroxylated surface. The adsorptions and reactions tend to occur more readily on the 'O<sub>w</sub>' site than on the 'O<sub>s</sub>' site based on the predicted adsorption energies. The stepwise decomposition of SiCl<sub>x</sub>(a) can be achieved by dehydrochlorination, and the reaction paths can be divided into three types of pathways: O<sub>w</sub>-path, O<sub>s</sub>-path and cross-path. We find that the O<sub>w</sub>-path is the most favored low energy path, followed by the cross-path and lastly the O<sub>s</sub>-path. The adsorption and decomposition of SiCl<sub>4</sub> following the O<sub>w</sub>-path can take place by three dehydrochlorination steps. Each dehydrochlorination can be achieved by three types of reactions: (1) SiCl<sub>x</sub> multi-site adsorptions; (2) the intermediate M<sub>x</sub> (x = 1–3) formation; (3) the dehydrochlorination giving stable Cl<sub>x</sub>Si(a) adsorbates (x = 1–3). We find that type (1) reactions control the SiCl<sub>x</sub> decomposition on the hydroxylated anatase (101) surface. Cl<sub>3</sub>Si–O<sub>w</sub>(a) and Cl<sub>2</sub>Si–O<sub>w</sub>O<sub>w</sub>(a) can be formed without thermal activation; however, the formation of ClSi–O<sub>s</sub>O<sub>w</sub>O<sub>w</sub>(a) needs to overcome a 33 kcal/mol energy barrier. Accordingly, the energetically downhill adsorption and decomposition reactions of SiCl<sub>4</sub> on the hydroxylated titania by stepwise dehydrochlorination processes is expected to produce Cl<sub>2</sub>Si–O<sub>w</sub>O<sub>w</sub>(a) with the most abundant concentration providing a reactive and strong molecular linker for the growth of Si thin films and other semiconductor quantum dots for opto-electronic device and solar cell fabrication applications. Take the growth of a III–V metal nitride, for example, the Cl<sub>2</sub>Si(O)O-functionalized surface can readily react with nitrogen and metal precursors (such as NH<sub>3</sub> and trimethyl indium) on the first surface layer as follows: Cl<sub>2</sub>Si(O)O(a) + NH<sub>3</sub> → 2HCl + HNSi(O)O(a); HNSi(O)O(a) + (CH<sub>3</sub>)<sub>3</sub>In → (CH<sub>3</sub>)<sub>2</sub>InNSi(O)O(a) + CH<sub>4</sub>.

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## Appendix A. Supplementary material

Supplementary data associated with this article can be found, in the online version, at <http://dx.doi.org/10.1016/j.comptc.2012.05.035>.

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